LVEM 5

Low Voltage Benchtop Electron Microscope Nanoscale from Your Benchtop





INTRODUCING THE LVEM 5



High Contrast Nanoscale Imaging

- Unmatched contrast of biologic and light material samples
- Image resolution as good as 1.2 nm
- Meaningful results without the need for heavy metal staining
- Versatility of having TEM, SEM and STEM imaging modes in one unit

Unique Benchtop Design

- The world's only benchtop TEM microscope
- Exceptional space-saving design
- Installs easily wherever imaging is needed most
- No special facility requirements needed (such as cooling, special power or an anti-vibration isolation)

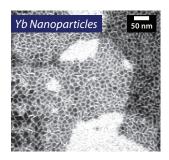
Simplified Workflow

- Easy to learn and operate
- User-friendly software interface and intuitive controls
- Quick sample exchange allows for high throughput imaging
- Image the same area of interest in TEM and SEM with high contrast

YOUR WAY TO ELECTRON MICROSCOPY



The LVEM 5 seamlessly combines 4 different imaging functionalities into one benchtop instrument, so samples no longer need to be displaced from one microscope to another. Furthermore, switching between imaging modes is easy, with the click of a button the same area of interest of a sample can be imaged in TEM, SEM and STEM modes.



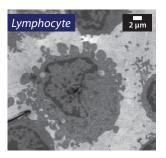
TEM Mode

LVEM 5 microscopes can be equipped with either a CCD or Scientic CMOS camera for Transmission Electron Microscopy imaging of nanoparticles and thin sections.



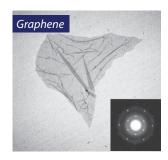
SEM Mode

A Backscatter Electron (BSE) detector offers a stereoscopic view of the sample. With the click of a button SEM mode is easily accessed to view the same area of interest for topographical information.



STEM Mode

Scanning Transmission Electron Microscopy is made possible with an added STEM detector. This mode allows for transmission images to be obtained from denser materials.

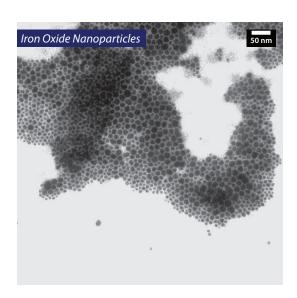


ED Mode

Electron Diffraction provides structural characterization of crystalline materials.

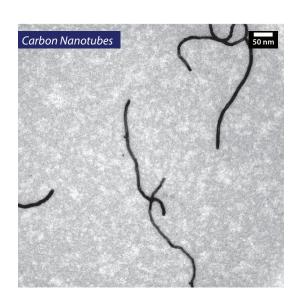
MATERIAL SCIENCE APPLICATIONS

The LVEM 5 has established itself as a valued asset to materials science research laboratories, providing the ability to rapidly obtain nanoscale images directly from the benchtop. High contrast and high resolution images of nano-structured materials provide meaningful sample data that can be used for complete morphological characterization and size distribution analysis, while phase composition and crystal structure can also be studied. With unmatched imaging resolution from a benchtop electron microscope, the LVEM 5 provides image data that would otherwise require a visit to a core facility and the use of a much larger and more complicated instrument. The LVEM 5 brings nanoscale to your benchtop.



Nanoparticles

Quantify the size, shape and structure of nanoparticles of gold, polymers and quantum dots directly from the benchtop.





2-Dimensional Materials

Quickly resolve size, thickness and crystal structure of 2-dimensional materials such as graphene and silicon with higher contrast than conventional EM.

Nanotubes

Image single-walled and multi-walled carbon nanotubes with clarity and precision.

LIFE SCIENCES APPLICATIONS

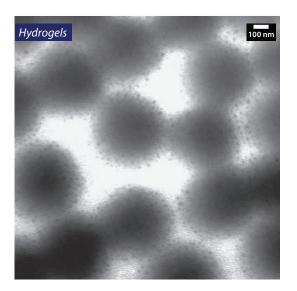
Conventional Transmission Electron Microscopes struggle to provide adequate contrast of organic materials, requiring the use of heavy metal staining to provide contrast. The LVEM 5 has overcome this limitation by means of its unique 5kV electron source, and is capable of providing high contrast of organic and other soft materials. These slower moving electrons interact more readily with organic materials, producing unmatched image contrast. Eliminating the need for stains provides for simplified sample preparation protocols and imaging of samples in their natural, unstained state.



Viruses

Study viruses such as adenovirus, rotavirus and tobacco mosaic virus, either in their natural state or with staining, a capability unique to LVEM.





Biologic Nanoparticles

Characterize essential morphological properties of protein-based, DNA-based, hybrid and synthetic particles with confidence.

Thin Sections

Clearly image biologic tissue thin sections such as brain, heart and kidney tissue without the necessity to stain.

KEY TECHNICAL FEATURES



Benchtop Design

A small footprint in the lab

The LVEM 5 is a benchtop instrument 90% smaller than classical TEMs.
Designed to be installed in individual labs, the LVEM 5 can be placed wherever imaging is routinely needed.



No Special Facilities

Installs almost anywhere

As a result of its small footprint and novel column architecture, the LVEM 5 does not require a dedicated room, anti-vibration isolation, special power supply or cooling of any kind, thereby simplifying the instrument's installation.



Permanent Magnet Lenses

No cooling required

The LVEM 5 and LVEM 25 are the only TEMs using permanent magnet lenses. This unique factor allows for the miniature architecture and eliminates any cooling requirements.



Field Emission Gun

High contrast electron source

A 5kV Schottky type FEG with very high brightness and spatial coherency allows for strong interactions between the emitted electrons and the samples. This is what provides the LVEM 5 with uniquely high contrast.



Controls & Software

Complete imaging control

The LVEM 5 comes with intuitive software for microscope operations and imaging. User operations are facilitated with simple adjustments for illumination, magnification and image optimization. The included PC and monitor allow for on-screen measurements and statistics, as well as live histogram correction and FFT.



Manipulator

Precise sample area selection

The LVEM 5 employs a motorized stage with joystick control for intuitive sample movement. Joystick sensitivity is dynamic, providing quick motion for low magnification sample screening and fine precision for high magnification imaging.



Ultra-High Vacuum Pumps

Clean column, clean imaging

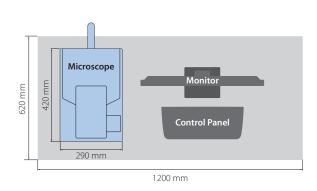
A maintenance free turbomolecular pump provides rapid evacuation of the airlock system and the silent and vibration free ion getter pumps produce an ultra-high vacuum imaging environment, free from contamination.

SPECIFICATIONS

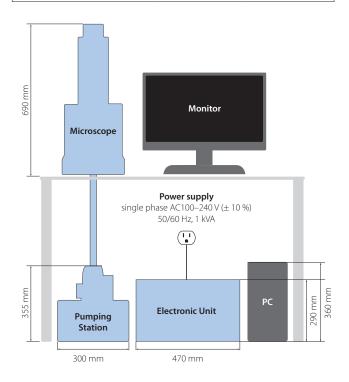
| OPERATION | | | |
|-----------------------------------|------------------------------|----------------|--|
| OPERATION | | F 147 | |
| Nominal accelerating voltage | 5 kV | | |
| Electron gun | Schottky field emission gun | | |
| Specimen size | standard Ø 3.05 mm TEM grids | | |
| Specimen movement | x, y: ± 1 mm | z: ± 0.3 mm | |
| Tilt holder | ± 22° | | |
| Specimen exchange time | approx. 3 min | | |
| IMAGING MODES | | | |
| BASIC TEM MODEL | | | |
| Projection lens | electrostatic single lens | | |
| Resolving power | 2.0 nm | | |
| Total magnification | 2,200 – 230,000× | | |
| TEM BOOST MODEL | | | |
| Projection lens | electrostatic double lens | | |
| Resolving power | 1.2 nm | | |
| Total magnification | 1,400 - 700,000× | | |
| ELECTRON DIFFRACTION | | | |
| Minimum probe size | | 100 nm | |
| Camera | CCD | sCMOS | |
| Camera length (binning 1x1) | 2,100 pixels | 2,390 pixels | |
| Camera constant (binning 1x1) | 36.3 nm pixels | 41.3 nm pixels | |
| STEM | | | |
| Resolving power | 2.0 nm | | |
| Maximum magnification | 250,000× | | |
| Maximum field of view | 25 × 25 μm | | |
| SEM (BSE DETECTOR) | | | |
| Resolving power | 4,0 nm | | |
| Maximum magnification | 100,000× | | |
| Maximum field of view | 200 × 200 μm | | |
| SCAN IMAGE CAPTURE | | | |
| up to 2,048 × 2,048 pxls / 8 bits | | | |
| | | | |

| TEM IMAGE CAPTURE | | |
|--------------------------------------|----------------------|-------------------------------------|
| | TEM Basic model | TEM Boost model |
| Camera | CCD | sCMOS |
| Sensor size | 2,048 × 2,048 pixels | $2,560 \times 2,160 \text{ pixels}$ |
| Digitalization | 12-bits | 16-bits |
| VACUUM | | |
| AIRLOCK SYSTEM | | |
| Diaphragm and turbomolecular | rpump | 10 ⁻⁵ mbar |
| OBJECT SPACE | | |
| lon getter pump | | 10 ⁻⁷ mbar |
| ELECTRON GUN | | |
| lon getter pump | | 10 ⁻⁹ mbar |
| POWER CONSUMPTION | | |
| Standby mode | | 40 VA |
| Operation consumption | | 300 VA |
| Maximum consumption | | 810 VA |
| DIMENSIONS AND WEIGHT | | |
| MICROSCOPE UNIT | | |
| Weight | | 25 kg |
| Dimensions (w \times d \times h) | Ž | 296 × 440 × 690 mm |
| AIRLOCK PUMPING STATION | | |
| Weight | | 17 kg |
| Dimensions (w \times d \times h) | 300 × 300 × 355 mm | |
| ELECTRONICS UNIT | | |
| Weight | | 19 kg |
| Dimensions (w \times d \times h) | 470 × 270 × 290 mm | |
| MAINS CONNECTION | | |
| Voltage/frequency | 1 | 00-240 V / 50-60Hz |
| INSTALLATION BENEFITS | | |
| No cooling water needed | | |
| Only single phase plug needed | | |

Installation Layout



Recommended table size: 1200 \times 700 mm Withstand load: 75 kg or more



Designed, Developed & Manufactured by:



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Please be sure to visit our website for more information at: www.lv-em.com

Your Local Distributor

The LVEM 5 is supported globally by sales and service offices in local markets. Please consult our website for the distributor in your country. You can also contact us directly for any questions you may have or to be referred to your distributor.